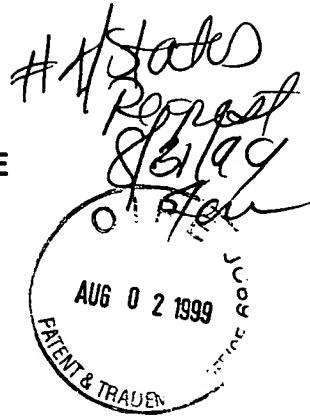


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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 1112
Examiner: To Be Assigned



In Re PATENT APPLICATION Of:

Applicant(s) : LIU et al.

Serial No. : 08/958,460

Filed : October 28, 1997

For : HIGH DENSITY PLASMA
CHEMICAL VAPOR DEPOSITION
PROCESS

Attorney Ref.: JIA 462

STATUS REQUEST

FEE ENCL. 6
Please charge any further
fee to our Deposit Account
No. 18-0002

Assistant Commissioner for Patents
Washington, DC 20231

Sir:

Please let us know the status of the above-identified application and when an
Action may be expected.

Respectfully submitted,



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RABON SERGENT
PRIMARY EXAMINER